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DEC 19 2002  
09/533,613  
PATENT & TRADEMARK OFFICE  
12/13/02

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PATENT

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DEC 24 2002  
TECHNOLOGY CENTER 2800

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Fred E. Stanke et al.

Application No.: 09/533,613

Filed: March 22, 2000

For: APPARATUS FOR IMAGING  
METROLOGY

Group Art Unit: 2877

Examiner: H.Q. Pham

**RESPONSE TO OFFICE ACTION  
MAILED AUGUST 14, 2002 AND  
REQUEST FOR ONE-MONTH  
EXTENSION OF TIME**

121 Spear Street, Suite 290  
San Francisco, CA 94105  
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#15/EO+  
T. 4/24/03  
1-9-03

Commissioner for Patents  
Washington, D.C. 20231

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope, addressed to: Commissioner for Patents, Washington, DC 20231 on December 13, 2002.

STALLMAN & POLLOCK LLP

Dated: 12/13/2002

By:

*Georgia K. Stith*  
Georgia K. Stith

Sir:

In response to the Office Action mailed August 14, 2002, and in conjunction with Applicants' request for a one-month extension to time, please amend the above-identified application as follows:

**IN THE SPECIFICATION:**

On page 23, lines 1 to 8, please replace the first paragraph on the page with the following. Attachment A provides a marked up version of the changed paragraph.

**Requested Change**

21  
--FIG. 9 shows a preferred embodiment integrated with a wafer process station in a fabrication line. For purposes of illustration and not limitation, the process station in the embodiment in FIG. 9 is a polisher. A polishing machine 1 and an integrated surface metrology station, ISMS 10, are shown. The polishing machine 1 comprises a polishing unit 14, loading

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